

Figure 1 (left). NiO thickness from 135 ALD cycles measured as a function of deposition temperature.

Figure 2 (right). NiO thickness from 135 ALD cycles measured as a function of precursor pulse length at a deposition temperature of 200°C.

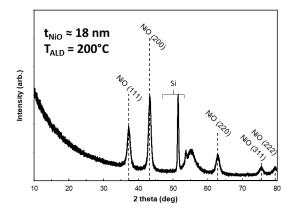


Figure 3. GIXRD scan of an 18 nm thick sample (135 ALD cycles) deposited at 200°C. Peaks were obtained from diffraction card 00-047-1049 (S) for cubic NiO.